

FIG. 1

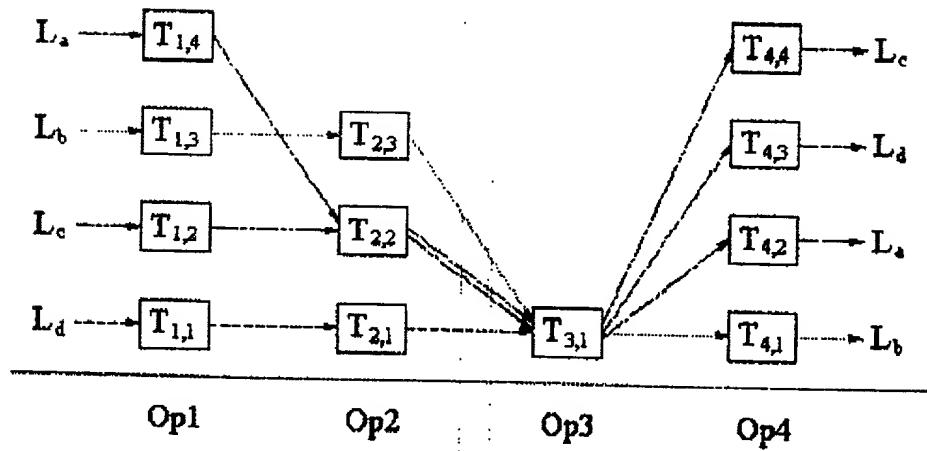


FIG. 2

Lot: L _a		Process Flow=PF101				Da
operation	Op1	Op2	Op3	Op4	---	
tool	T _{1,4}	T _{2,1}	T _{3,1}	T _{4,2}	---	
Yd _a						
wafer	W _{4,1}	W _{4,2}	W _{4,3}	W _{4,4}	---	
yield	Y _{4,1}	Y _{4,2}	Y _{4,3}	Y _{4,4}	---	

FIG. 3

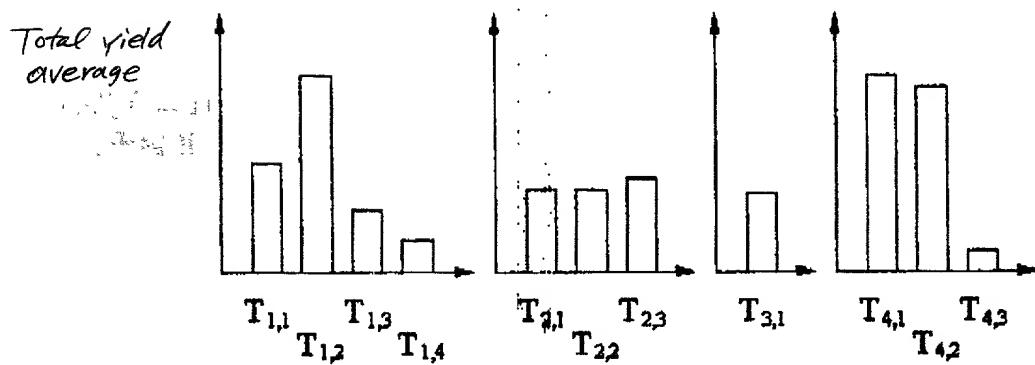


FIG. 4